

RESPONSE UNDER 37 C.F.R. § 1.116  
-- EXPEDITED PROCEDURE --  
EXAMINING GROUP 2800

Our Docket No: 42P10058

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Han-Ming Wu et al.

Examiner: Nguyen, Hung

Serial No: 09/752,938

Art Unit: 2851

Filed: December 29, 2000

For: Purging Gas from a  
Photolithography Enclosure  
Between a Mask Protective  
Device and a Pattern Mask

RESPONSE TO OFFICE ACTION

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In Response to the Final Office Action mailed on April 25, 2003, the Applicants respectfully request that the Examiner enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

July 23, 2003

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence

Signature

July 23, 2003

Date

RECEIVED  
AUG - 1 2003  
TECHNOLOGY CENTER 2800